

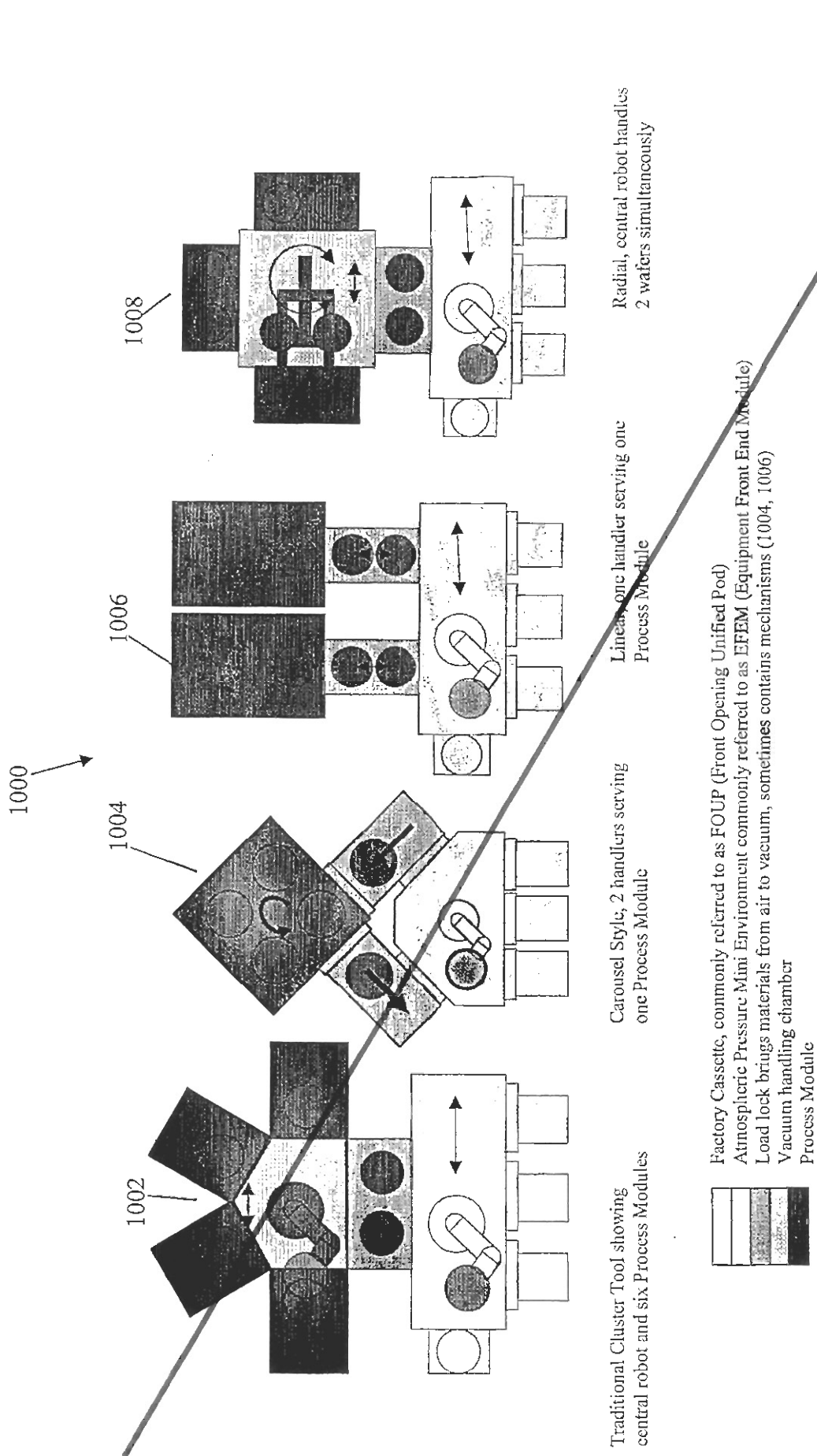


FIG. 1

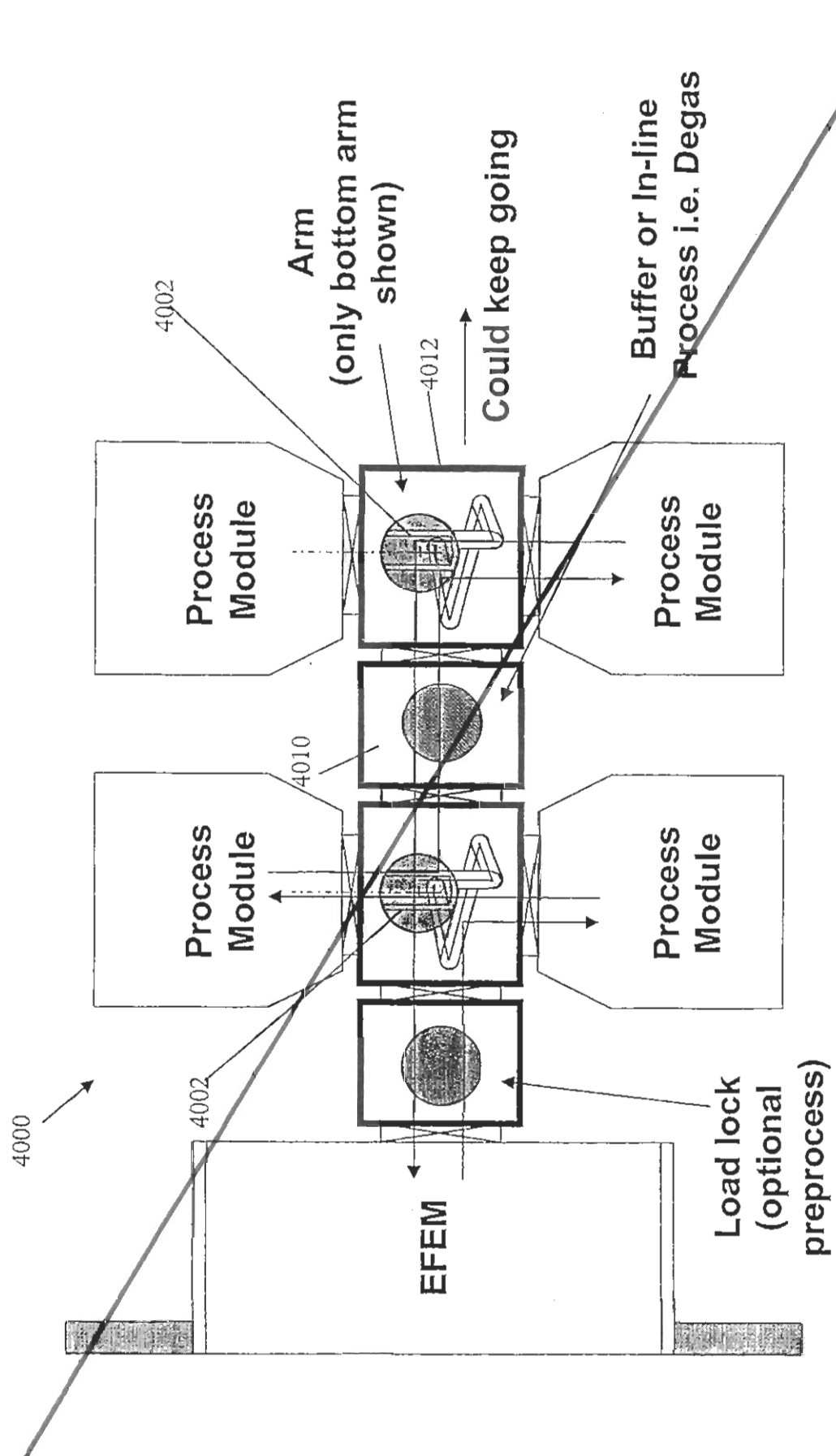


FIG. 5

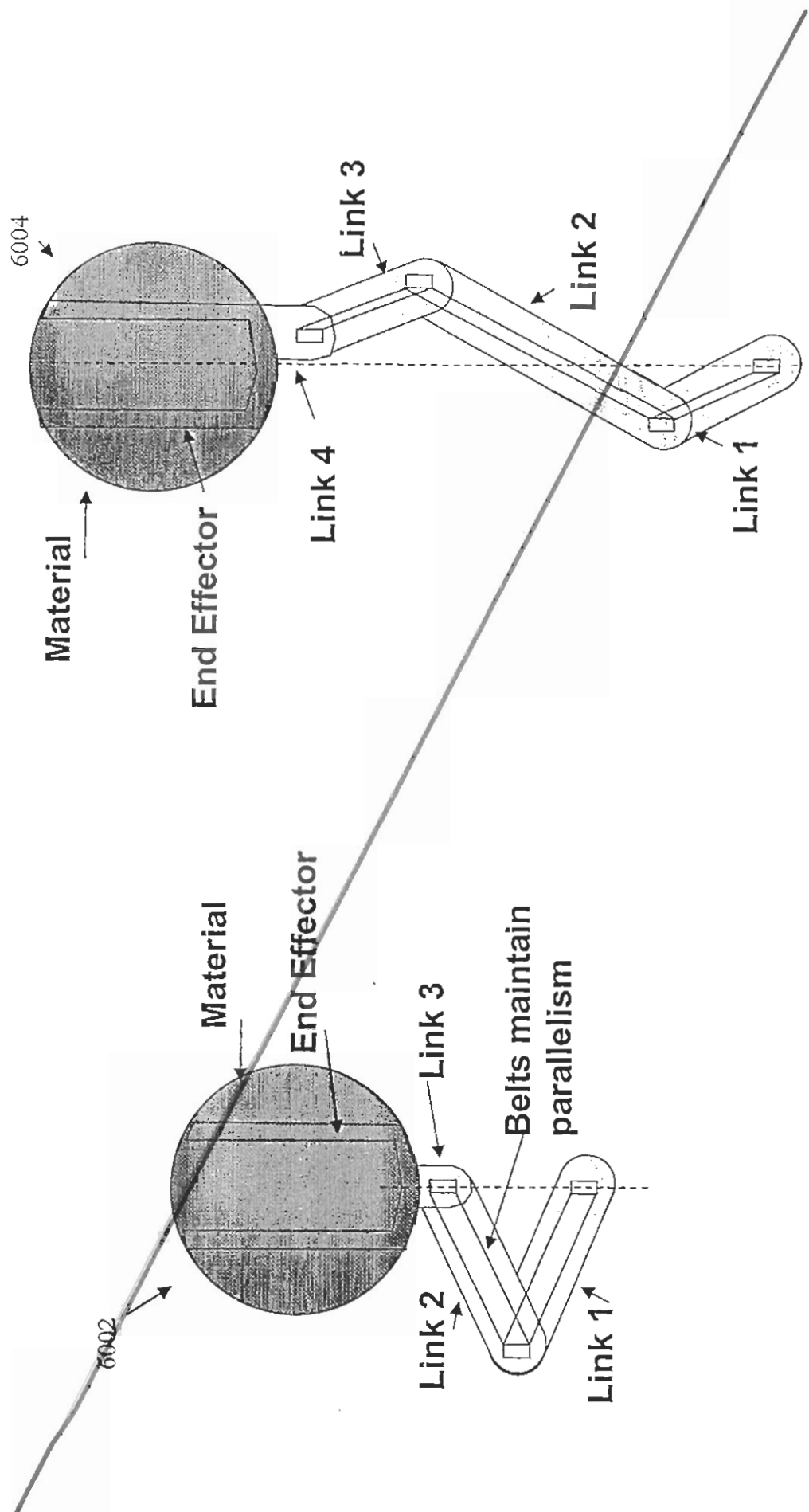


FIG. 6

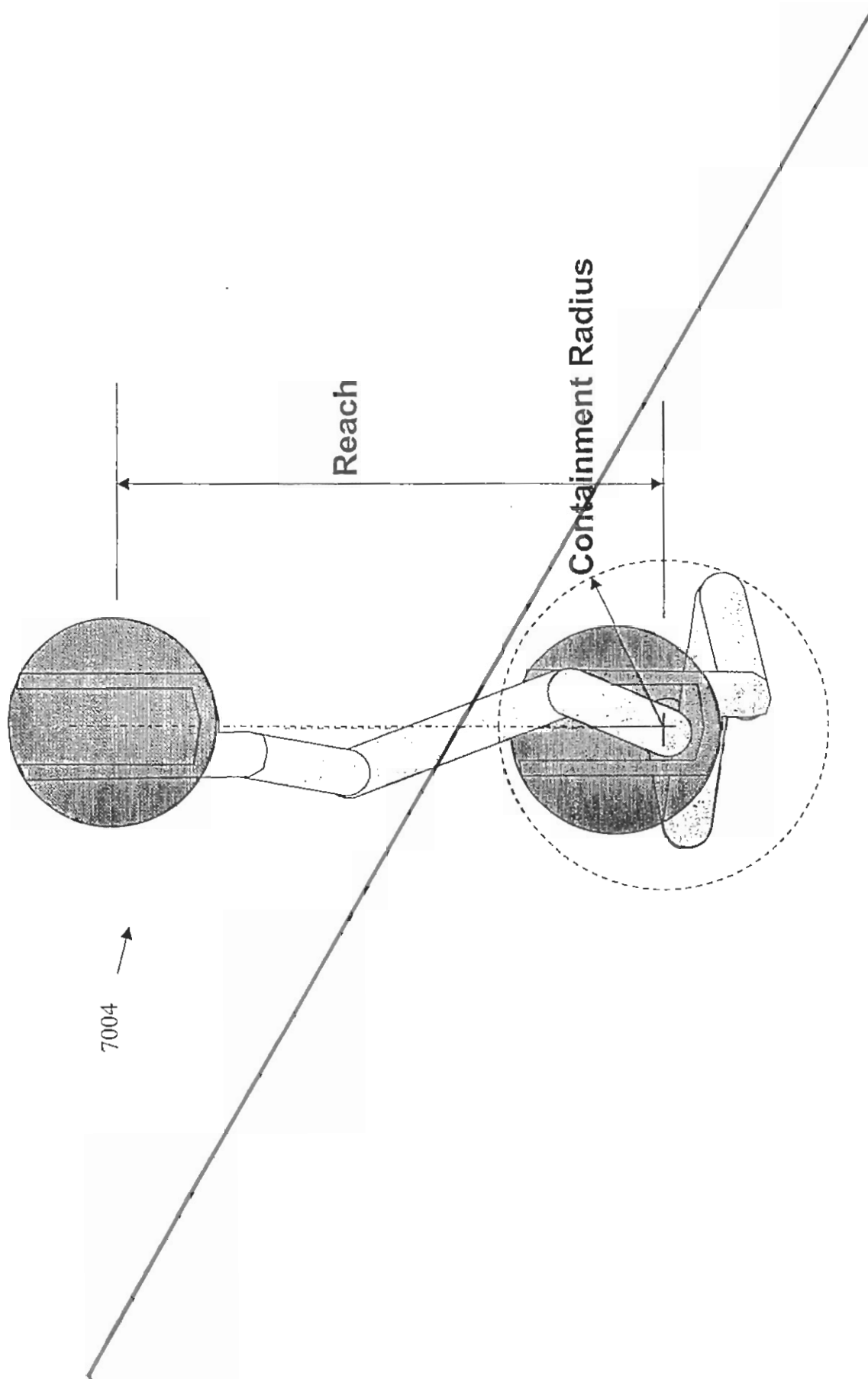


FIG. 7

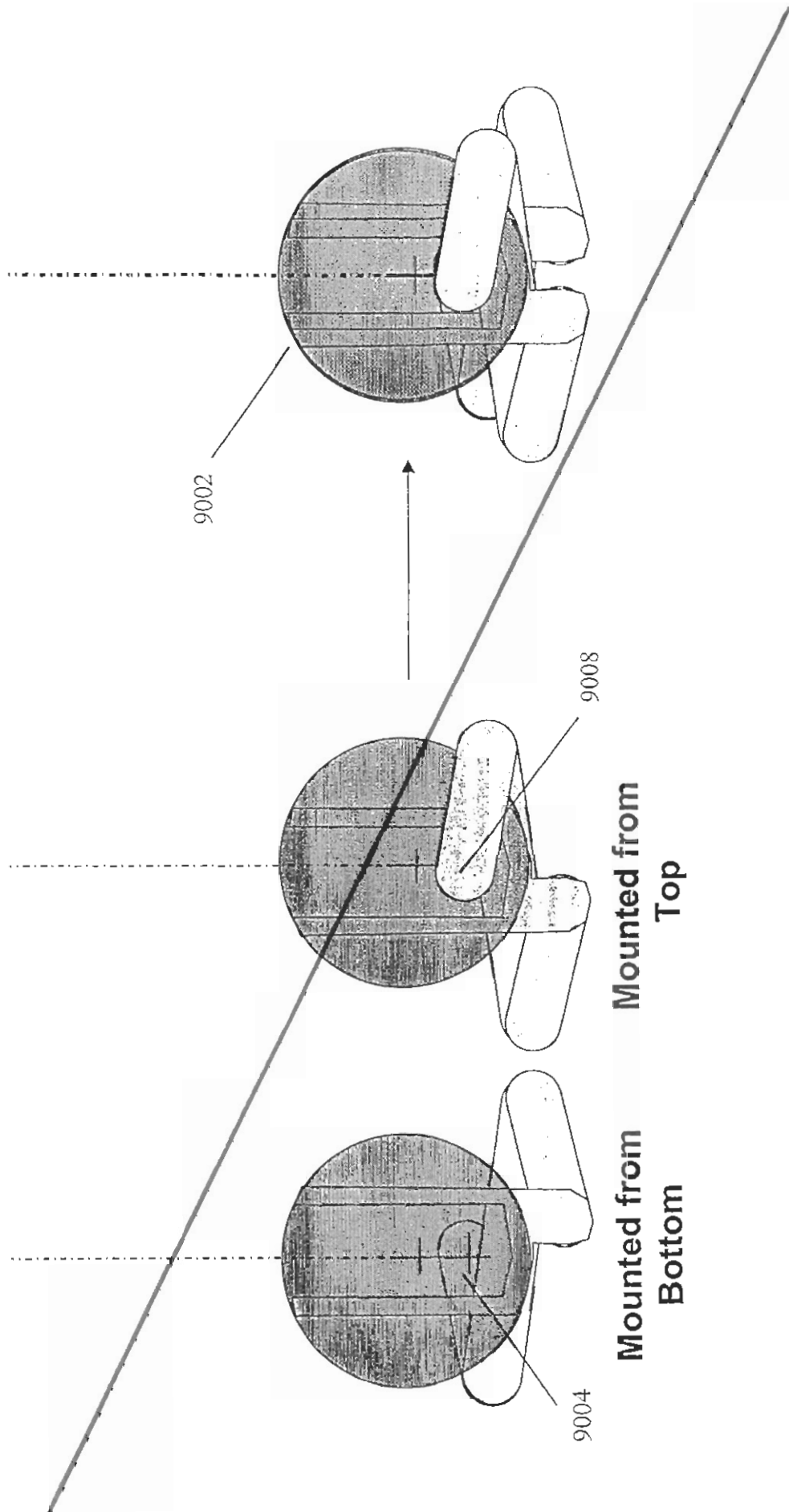
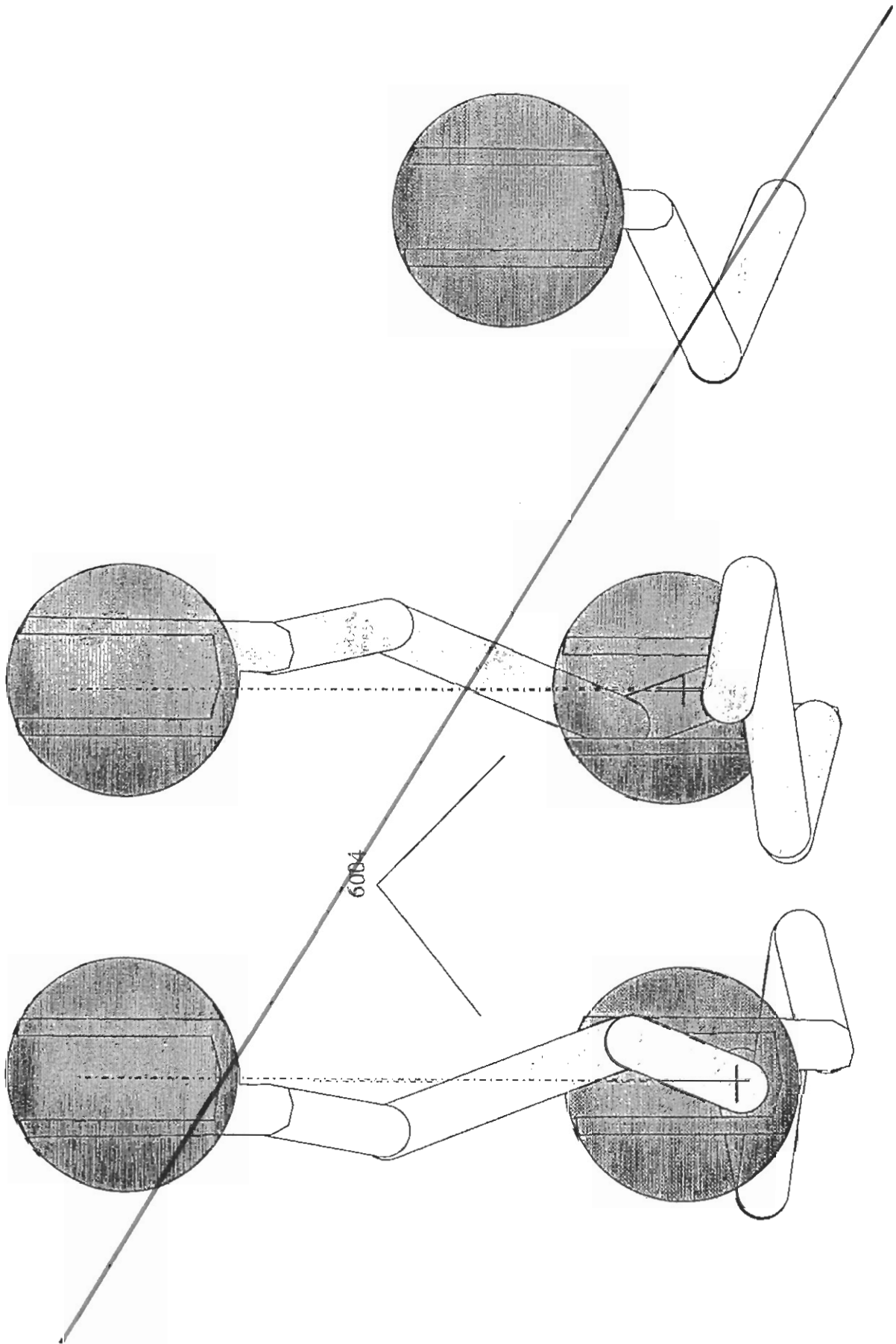


FIG. 9



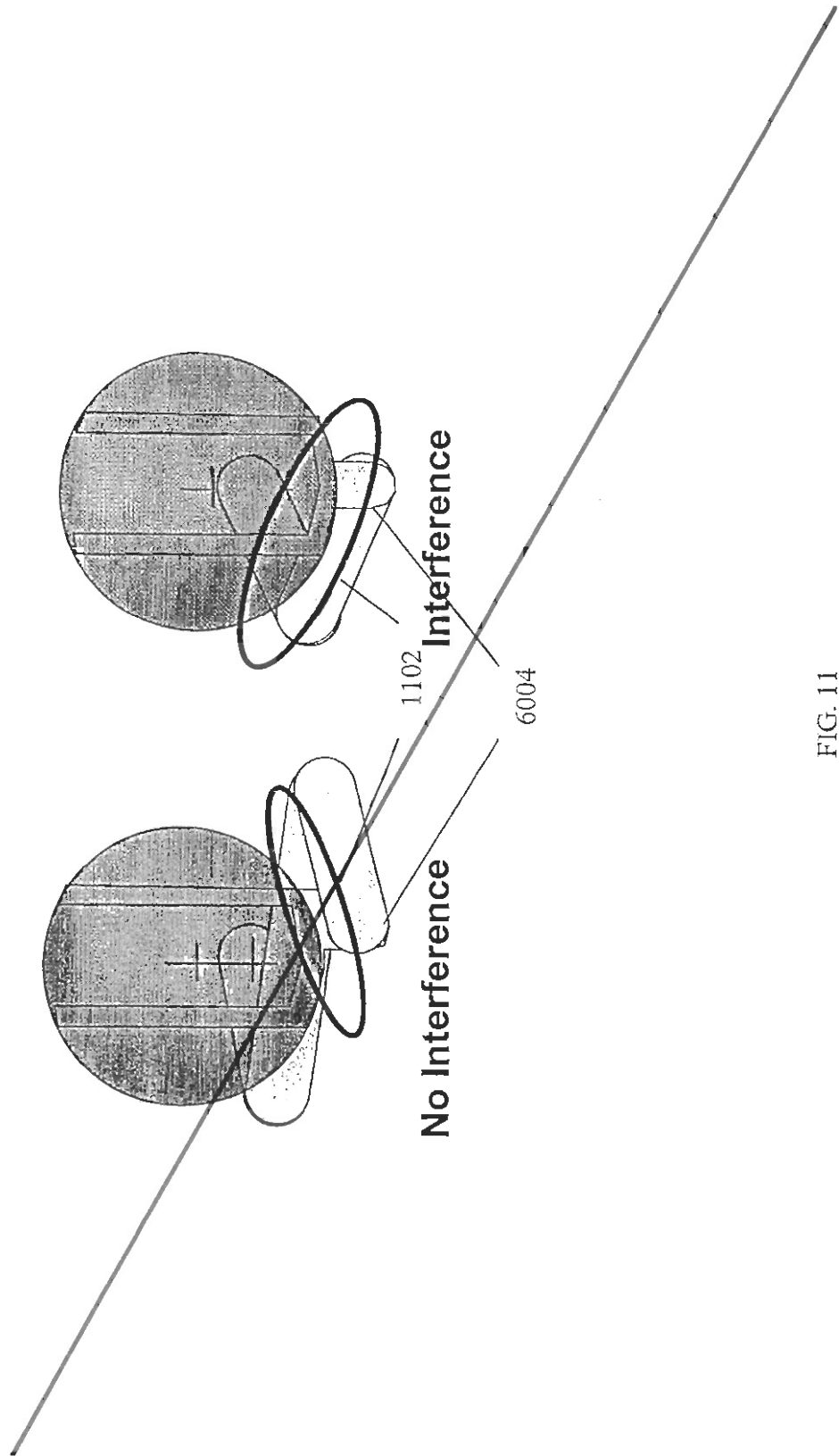


FIG. 11

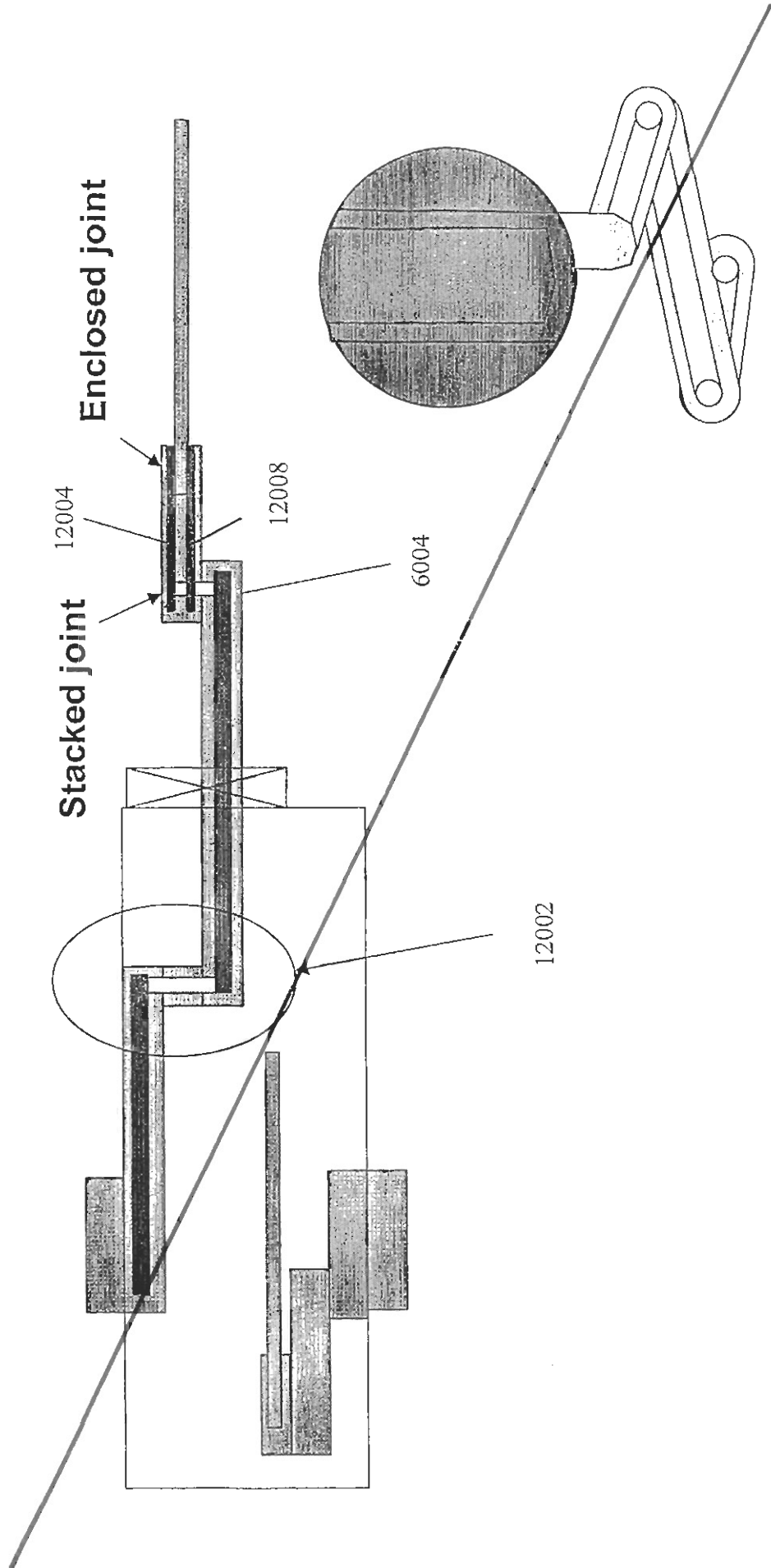


FIG. 12

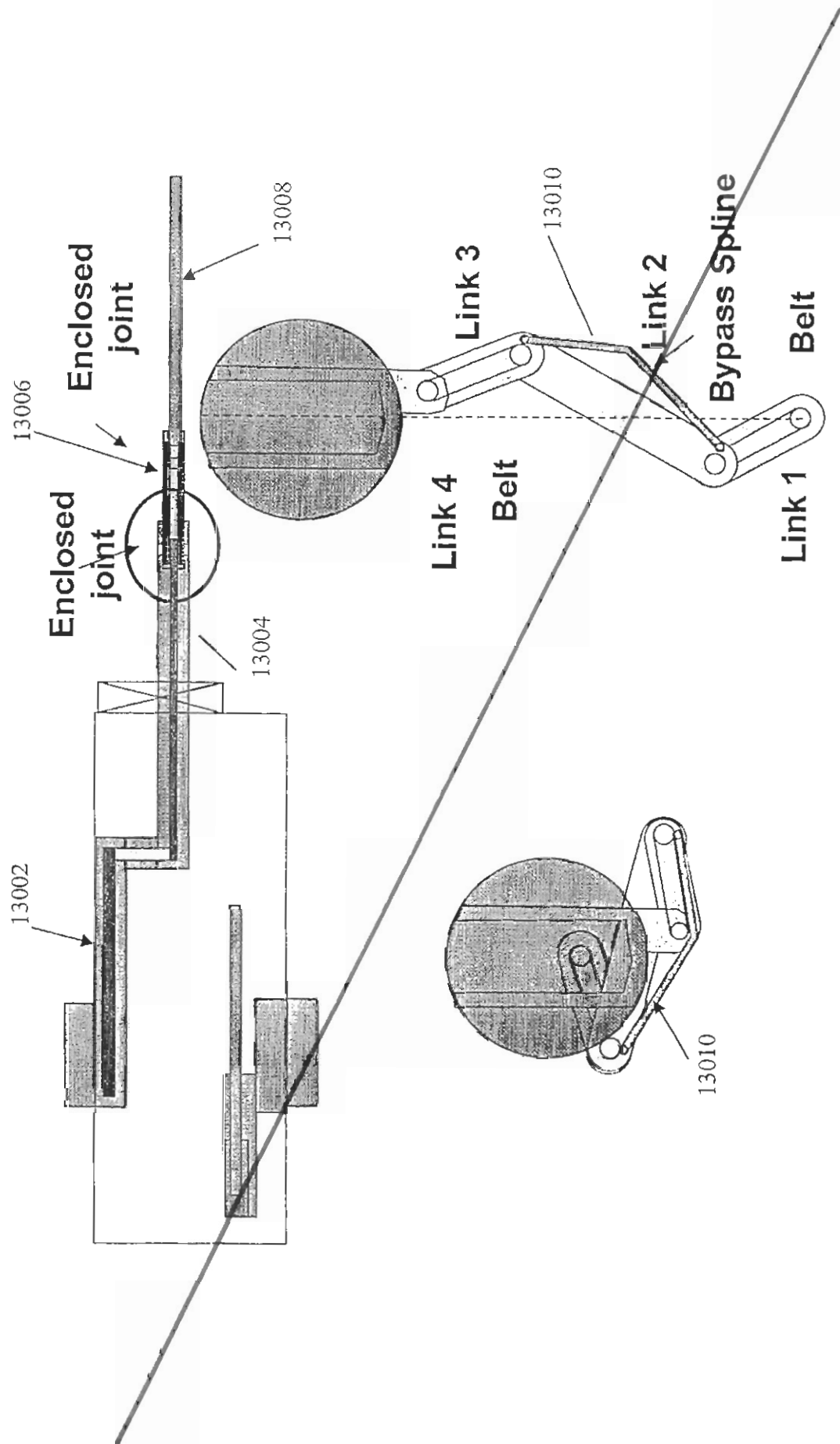


FIG. 13

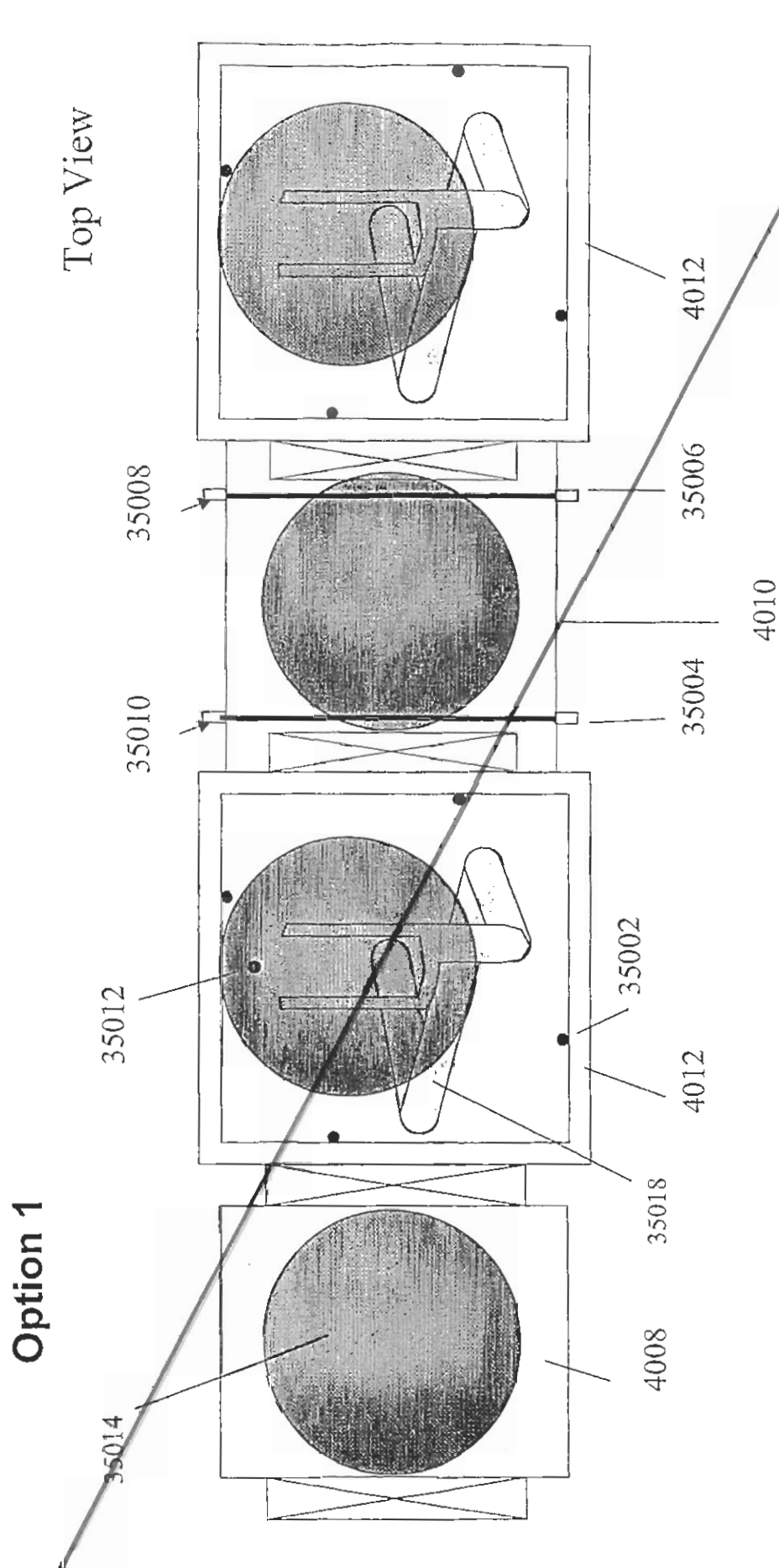
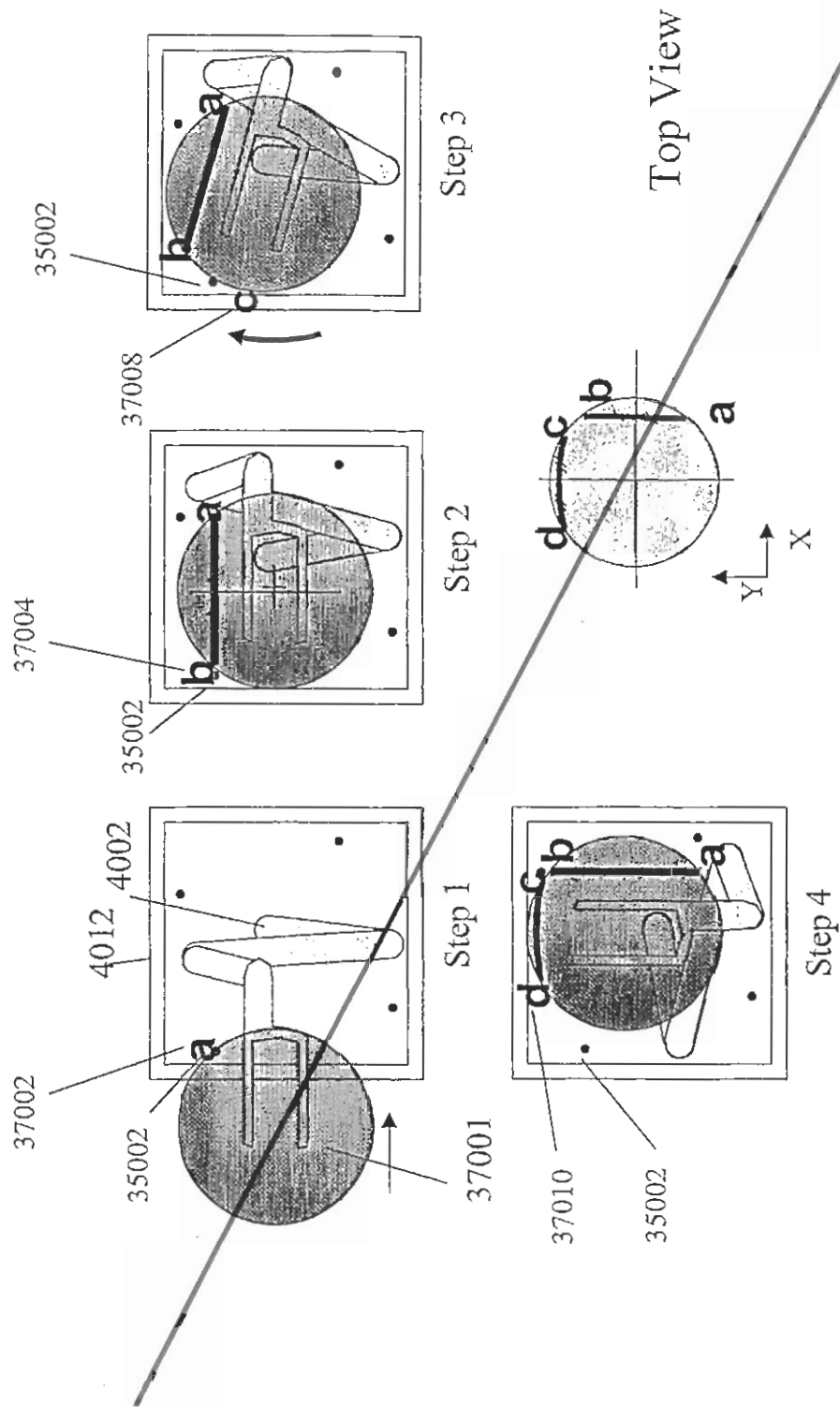


FIG. 35



Pattern scribed by Sensor 1 on wafer during retract (a -> b)
And CW rotation (c -> d) may determine wafer location in x,y plane

FIG. 37

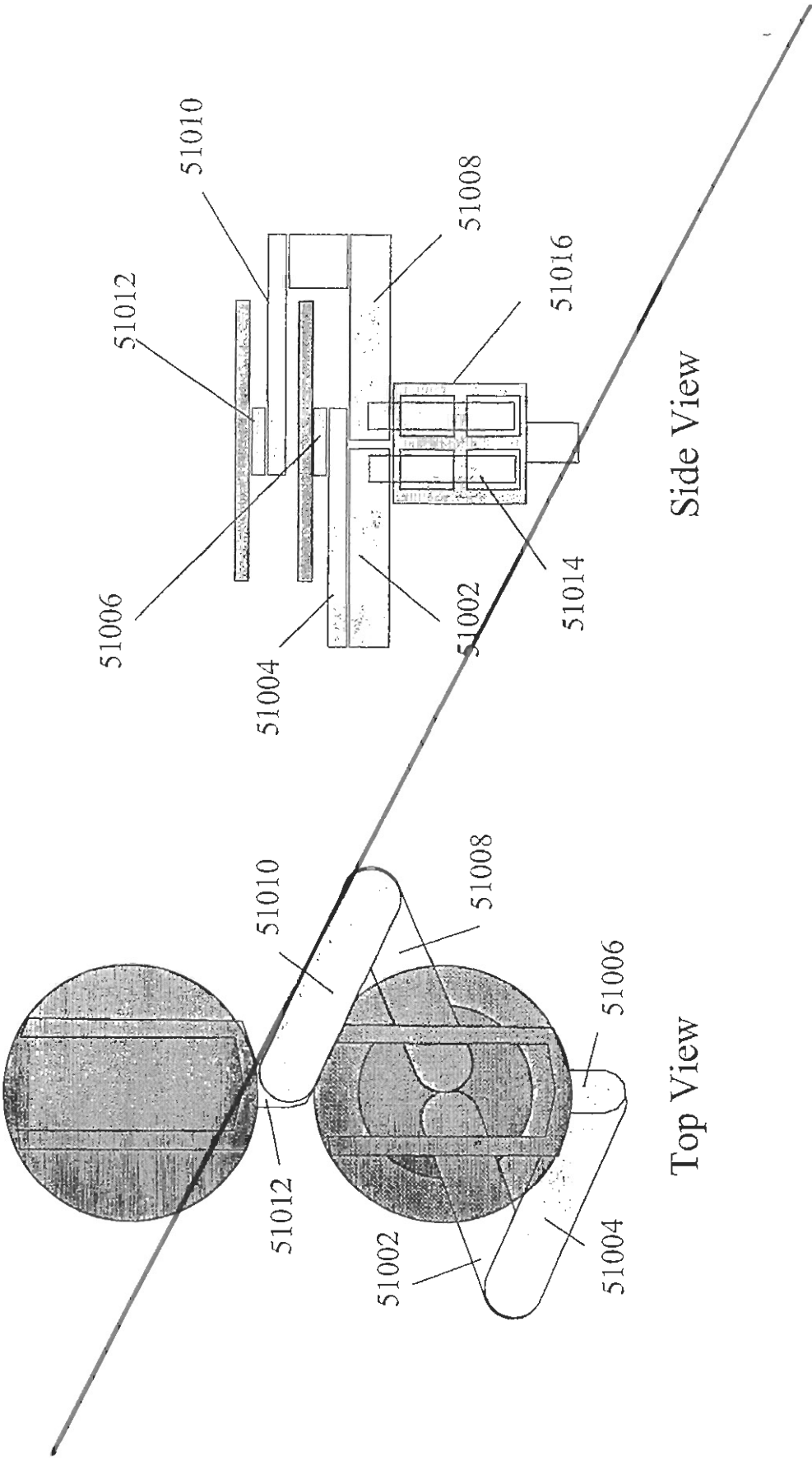


FIG. 51

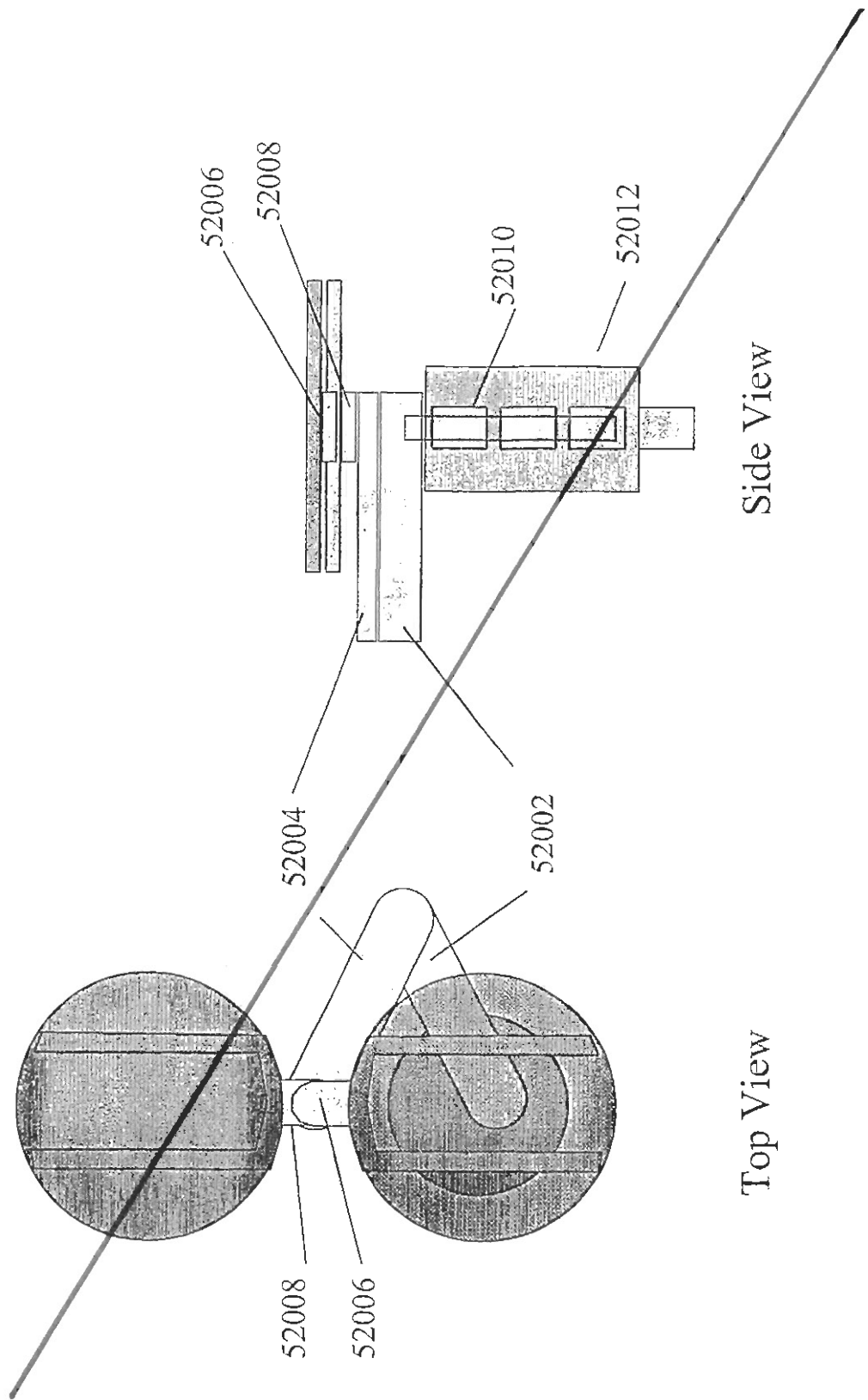


FIG. 52

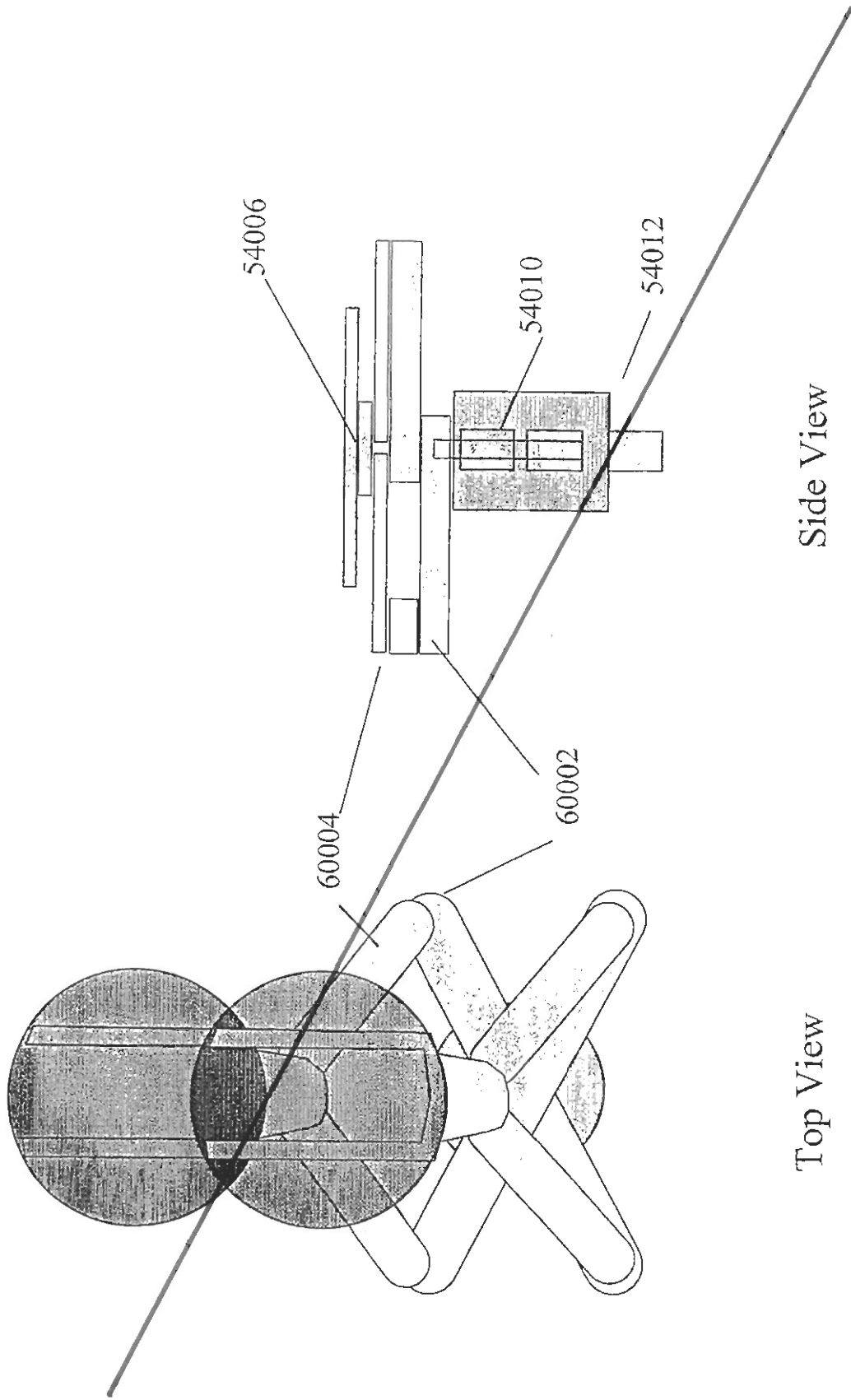


FIG. 60

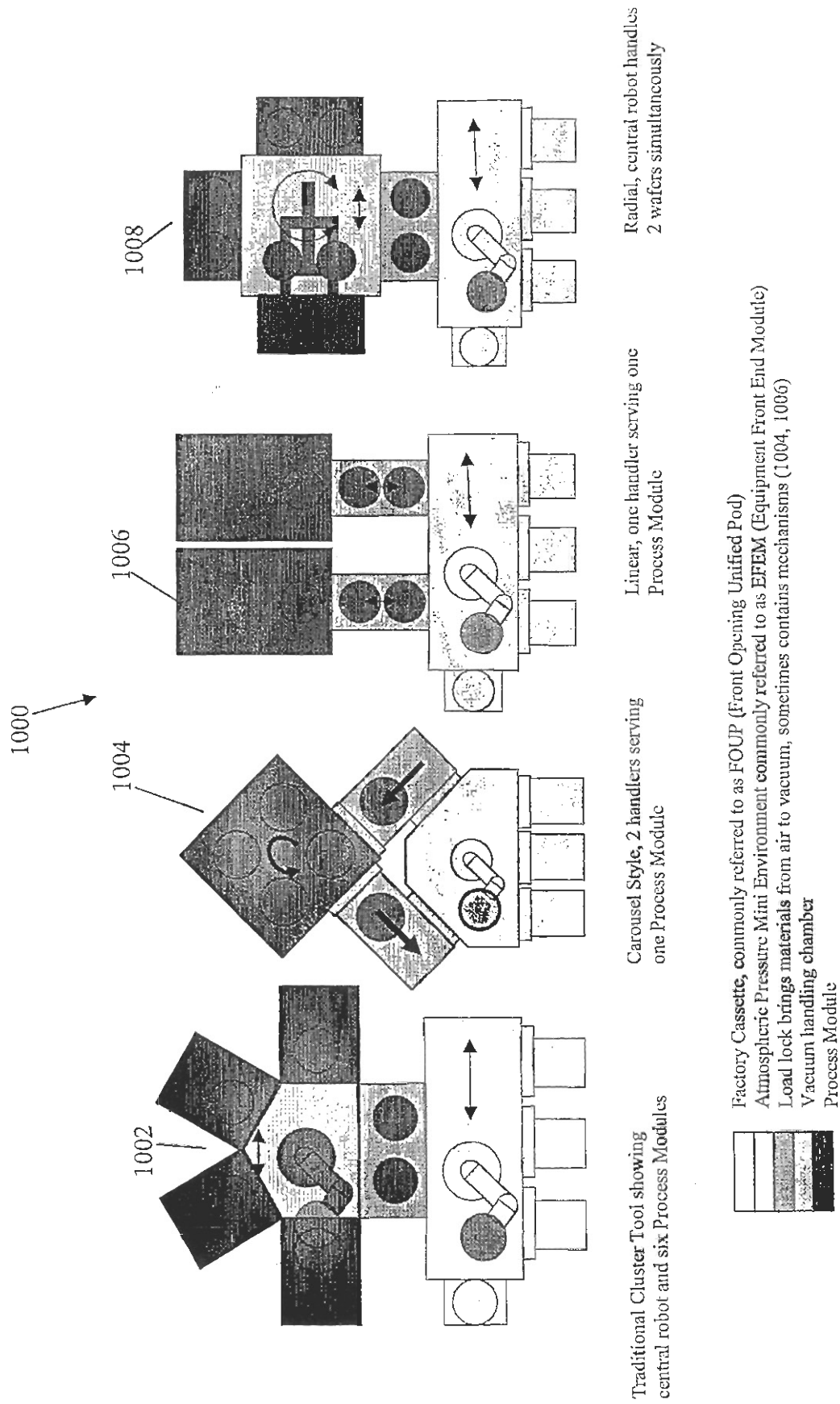


FIG. 1

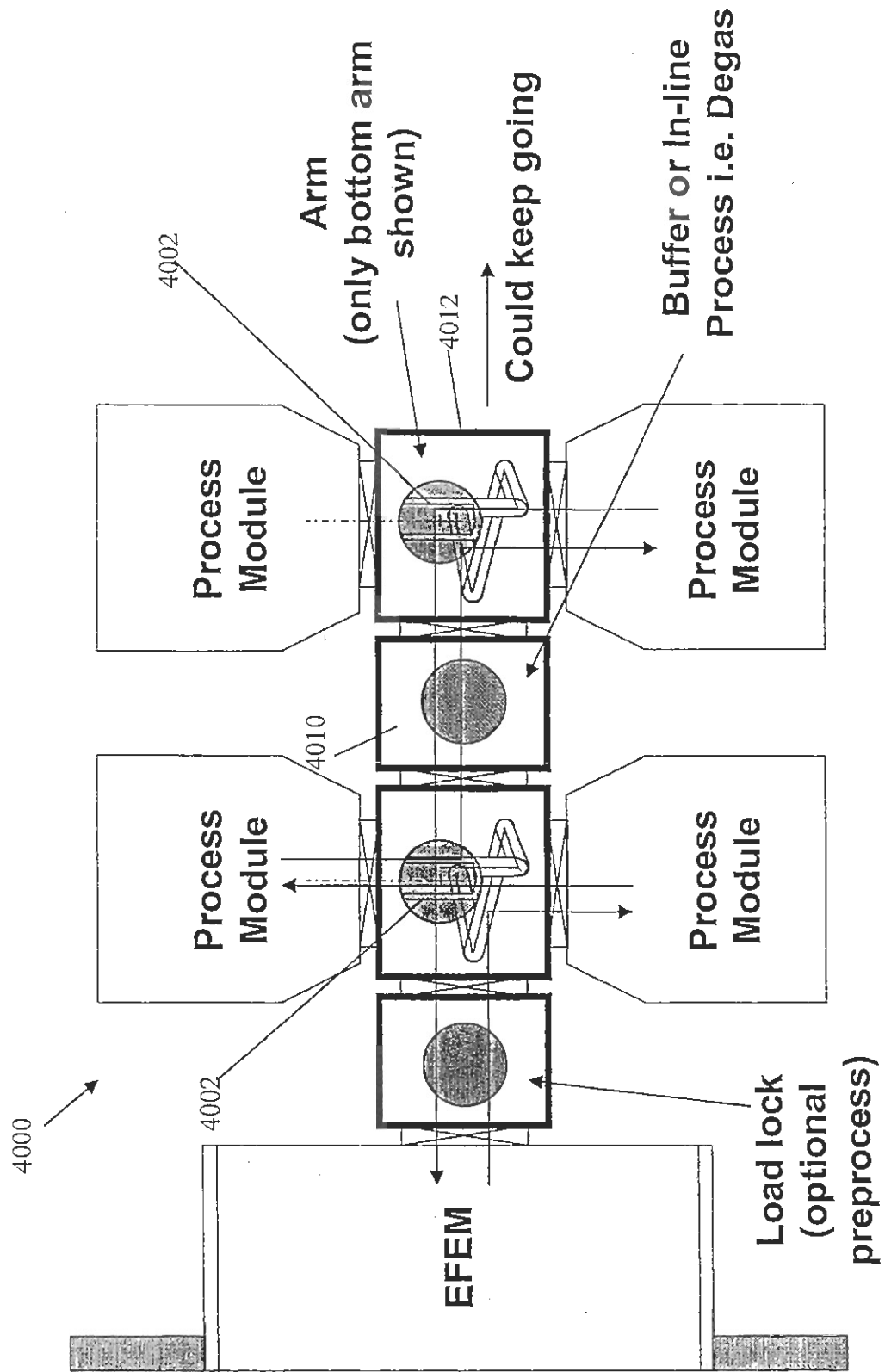


FIG. 5

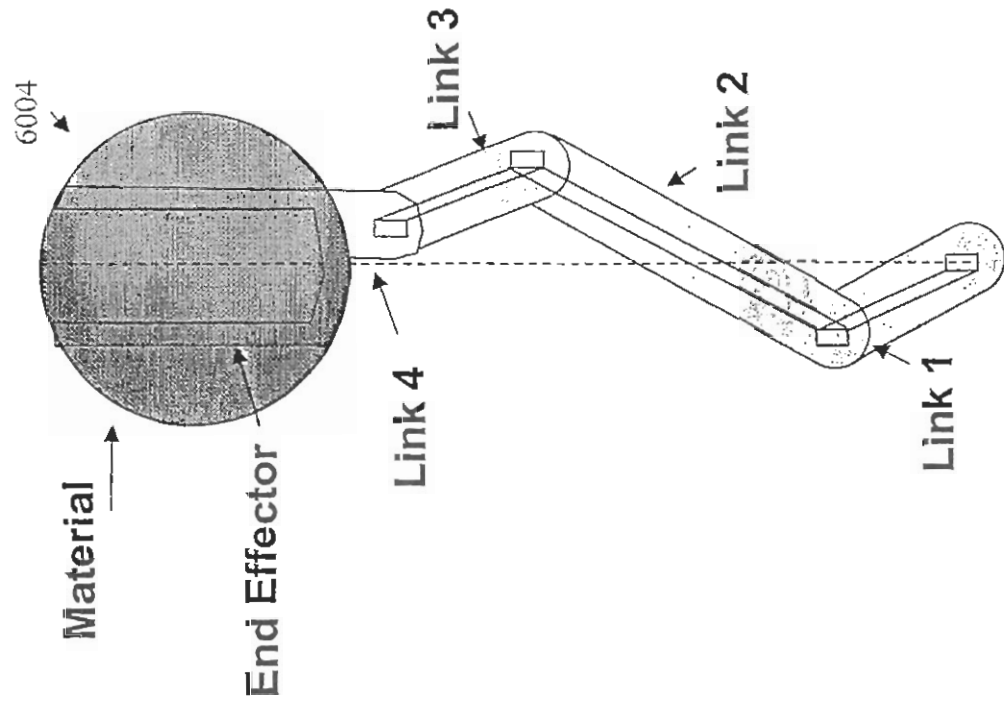
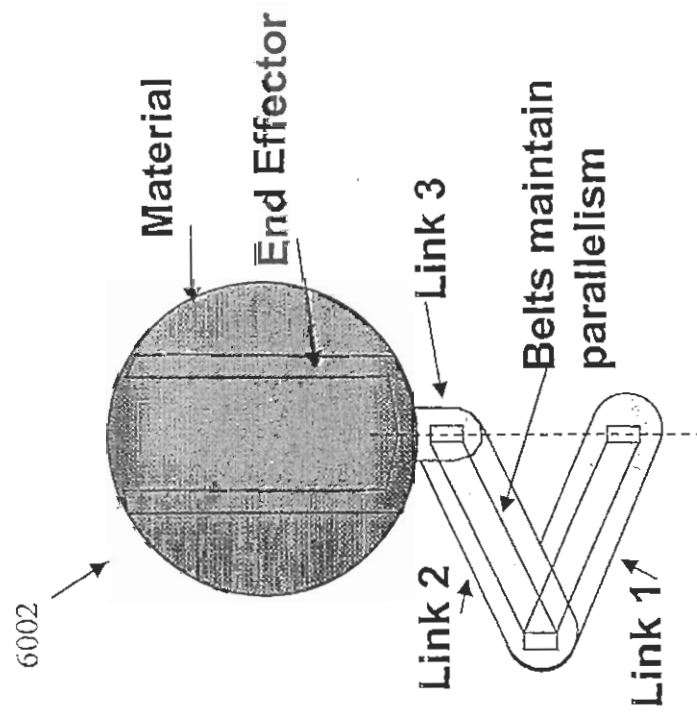


FIG. 6

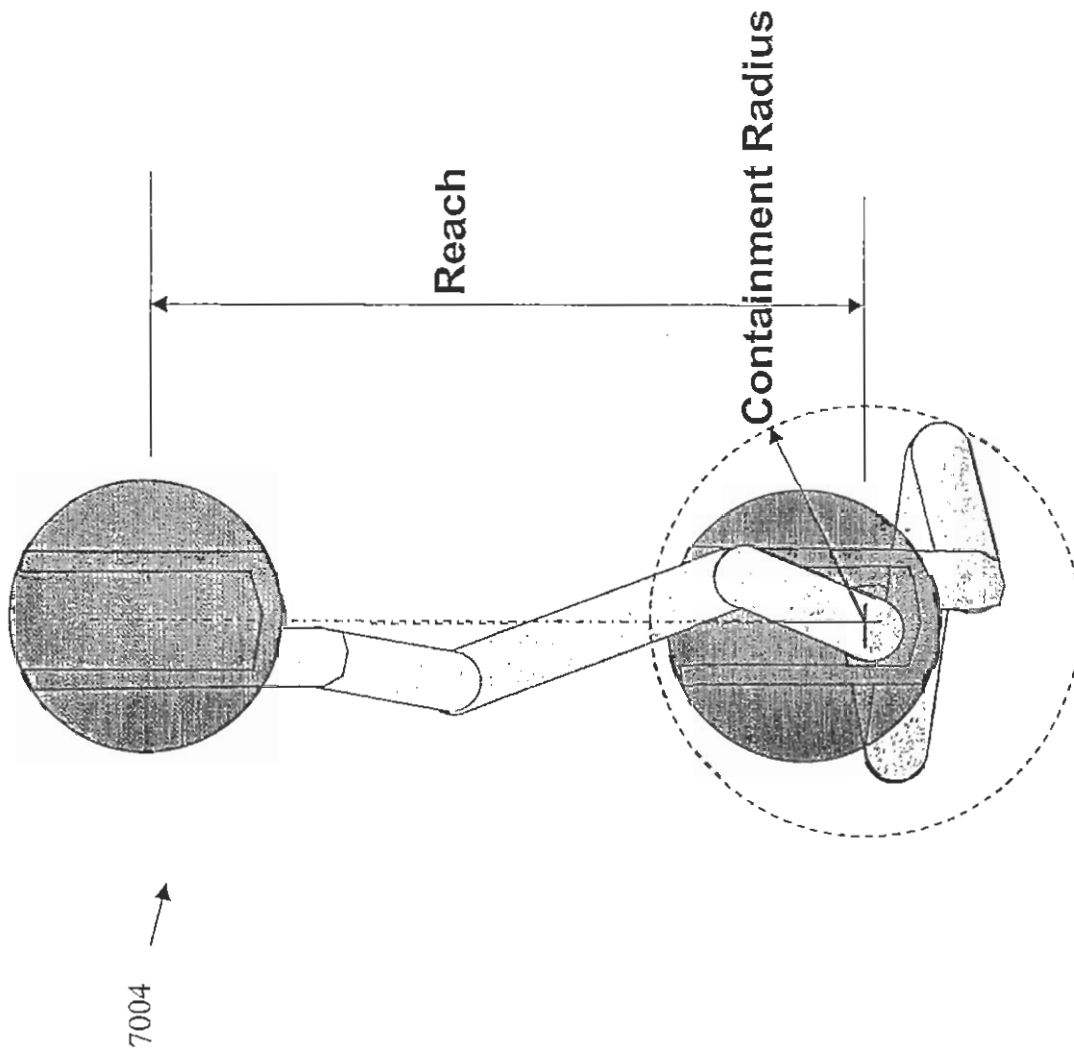


FIG. 7

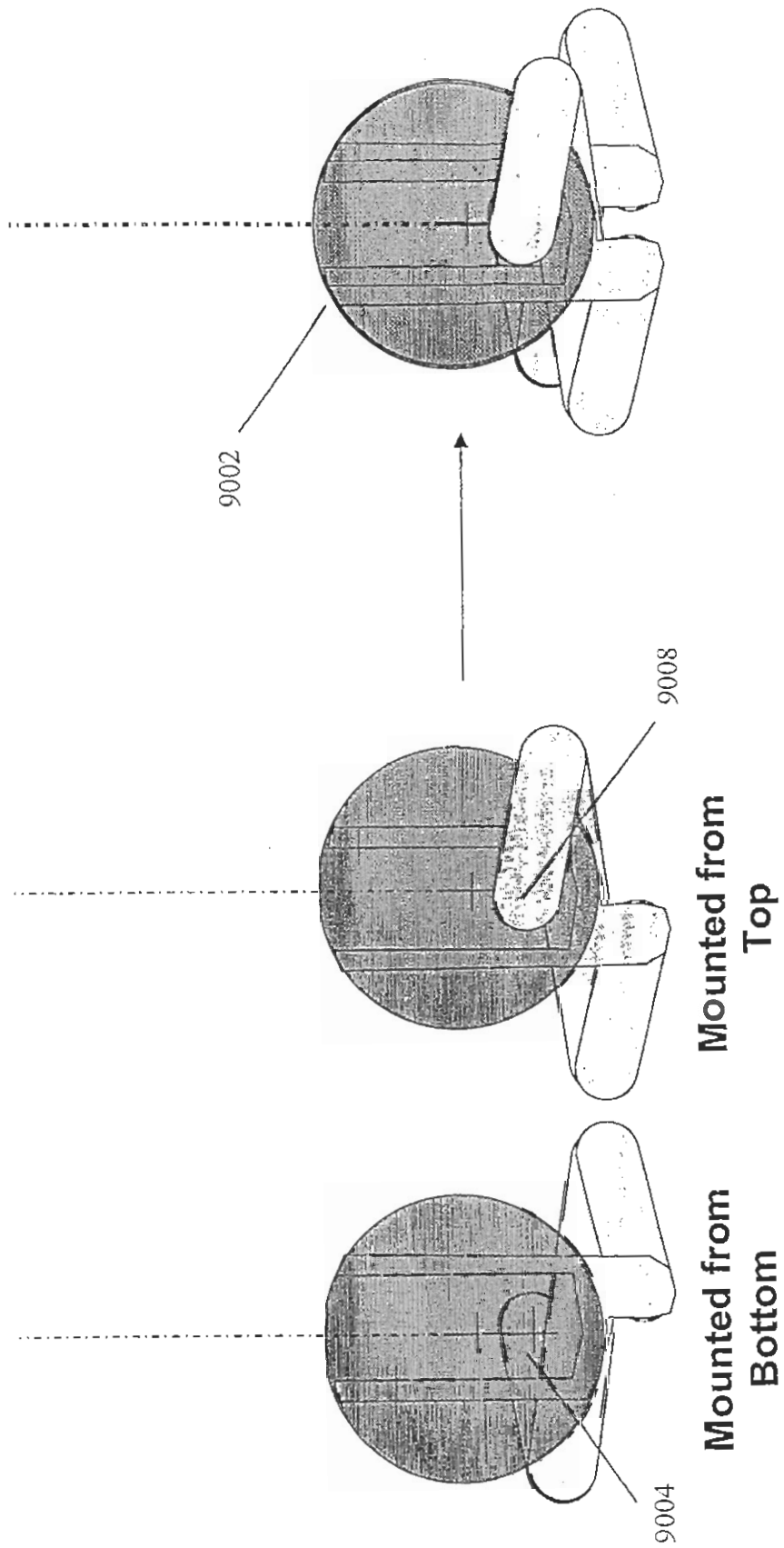


FIG. 9

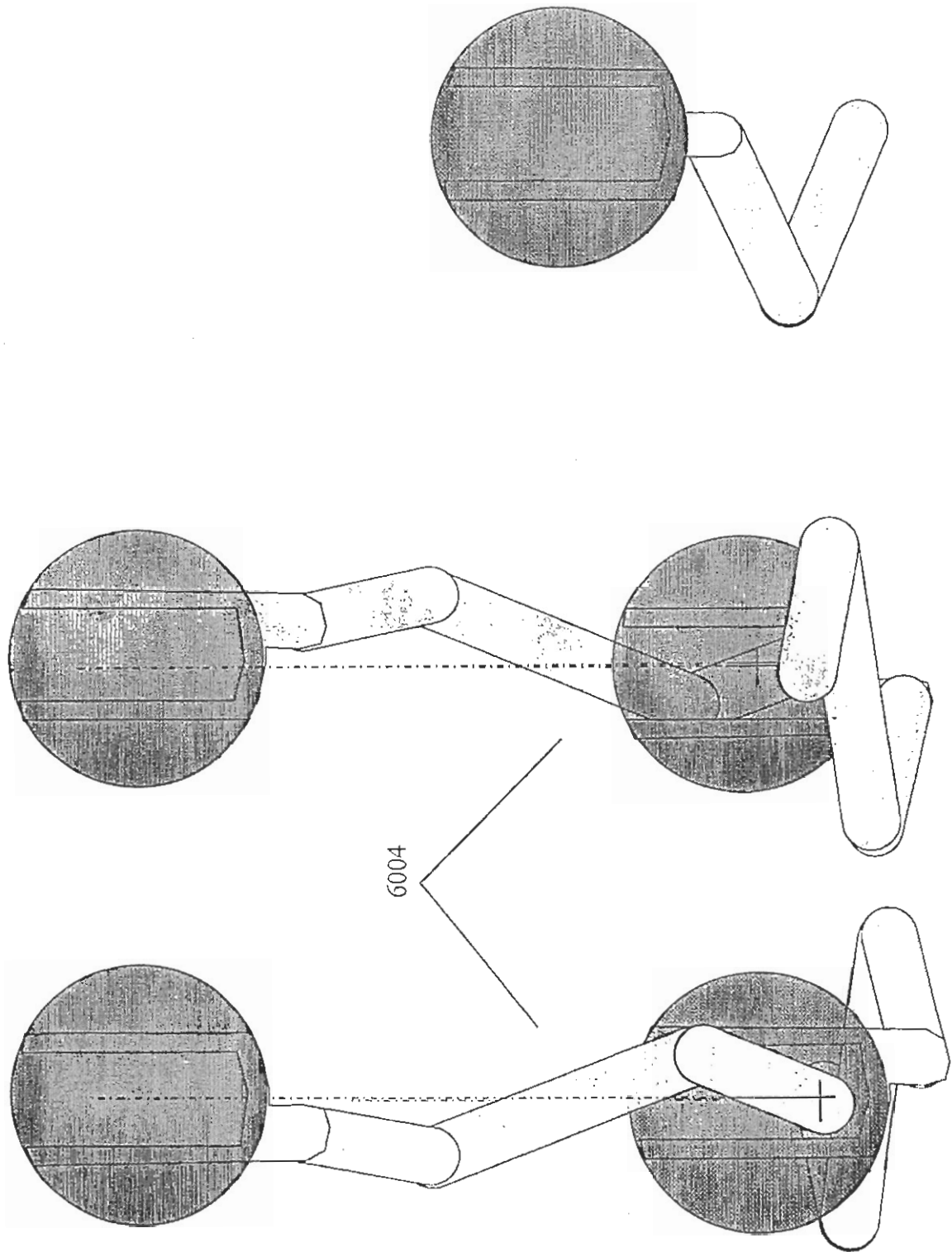


FIG. 10

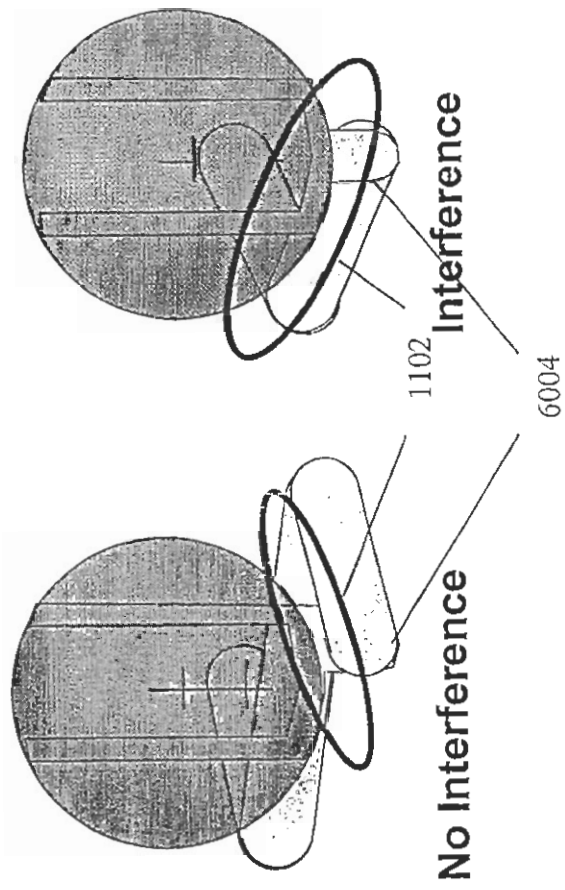


FIG. 11

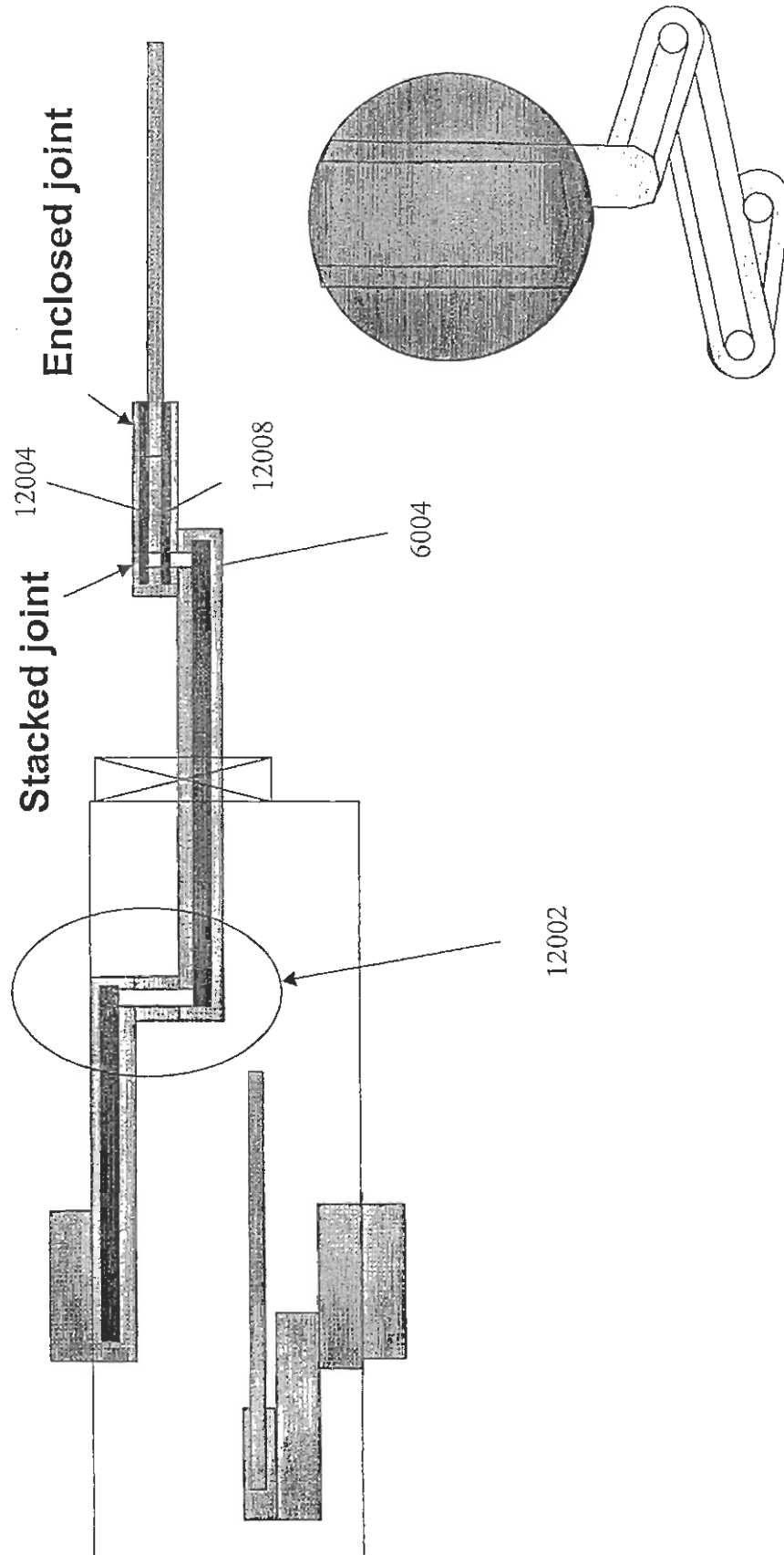


FIG. 12

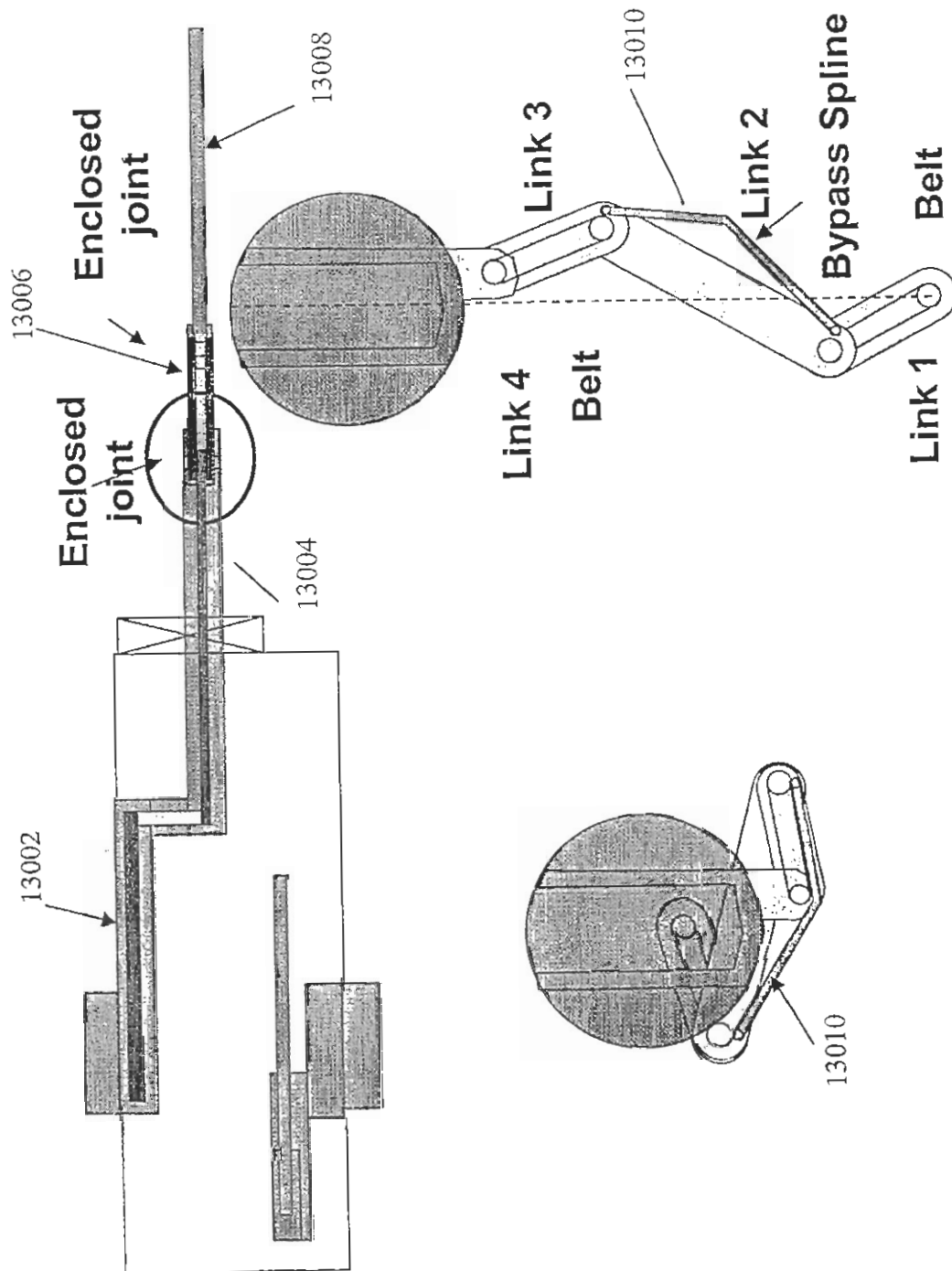


FIG. 13

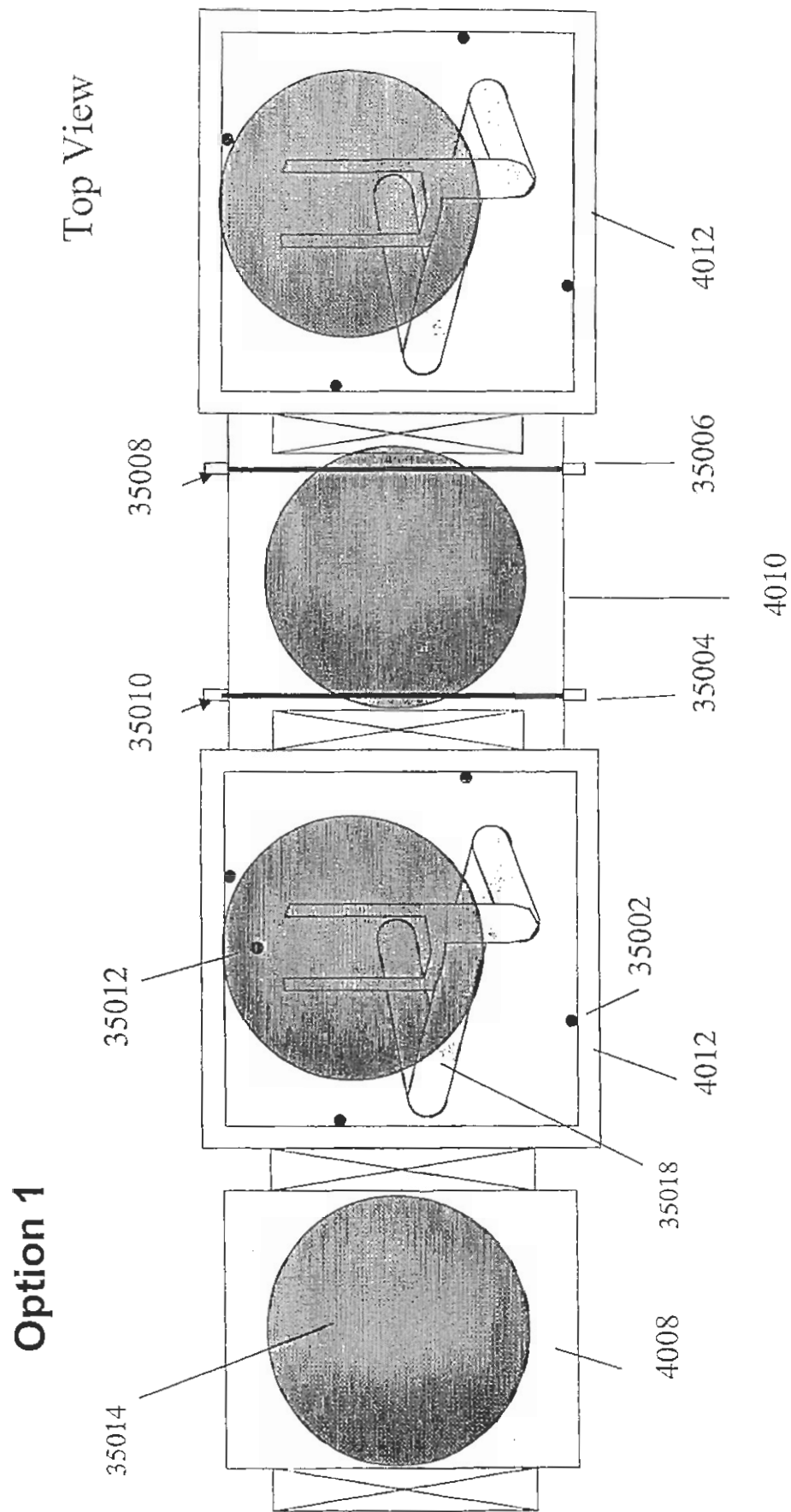
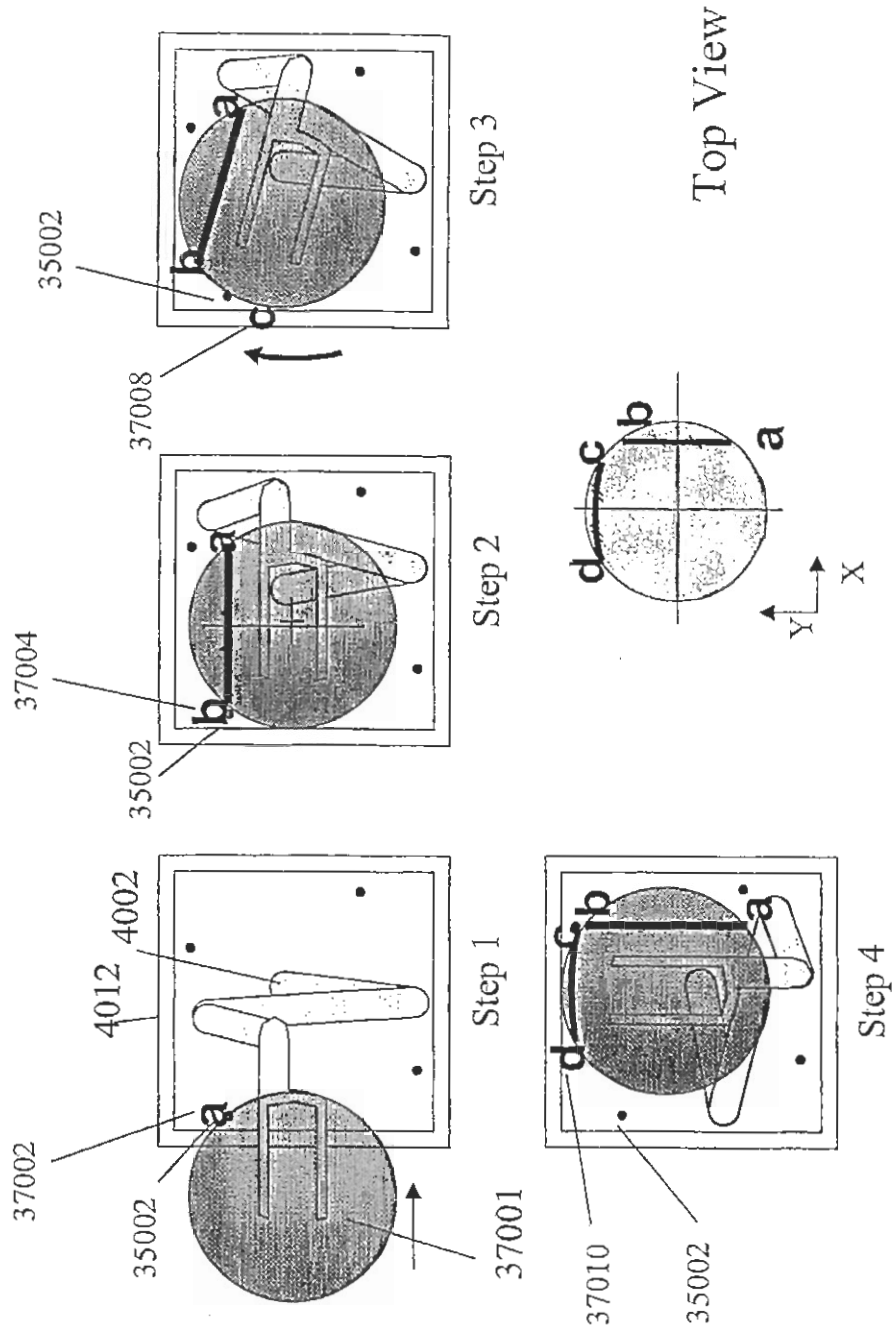


FIG. 35



Pattern scribed by Sensor 1 on wafer during retract (a -> b)
And CW rotation (c -> d) may determine wafer location in x,y plane

FIG. 37

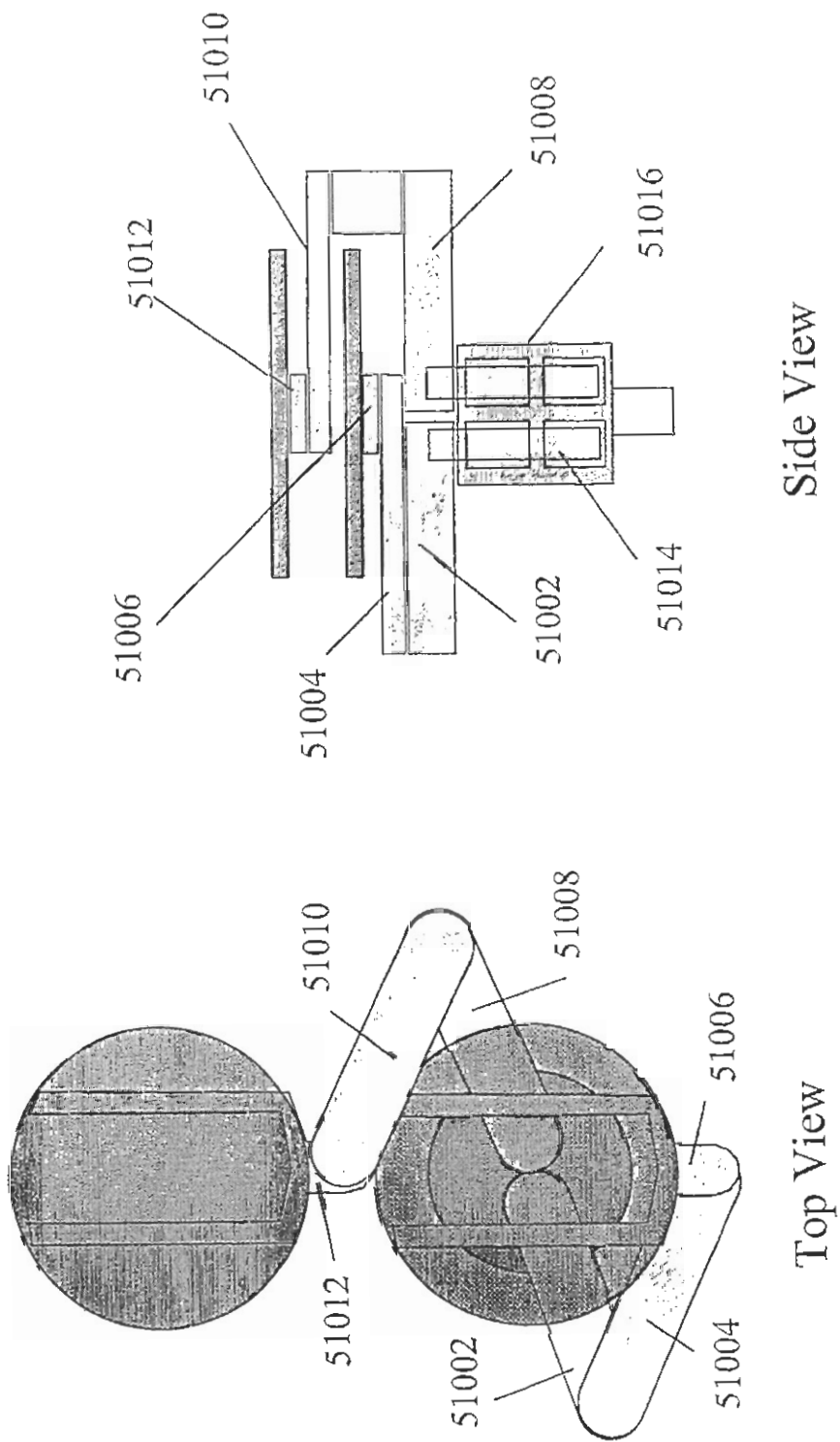


FIG. 51

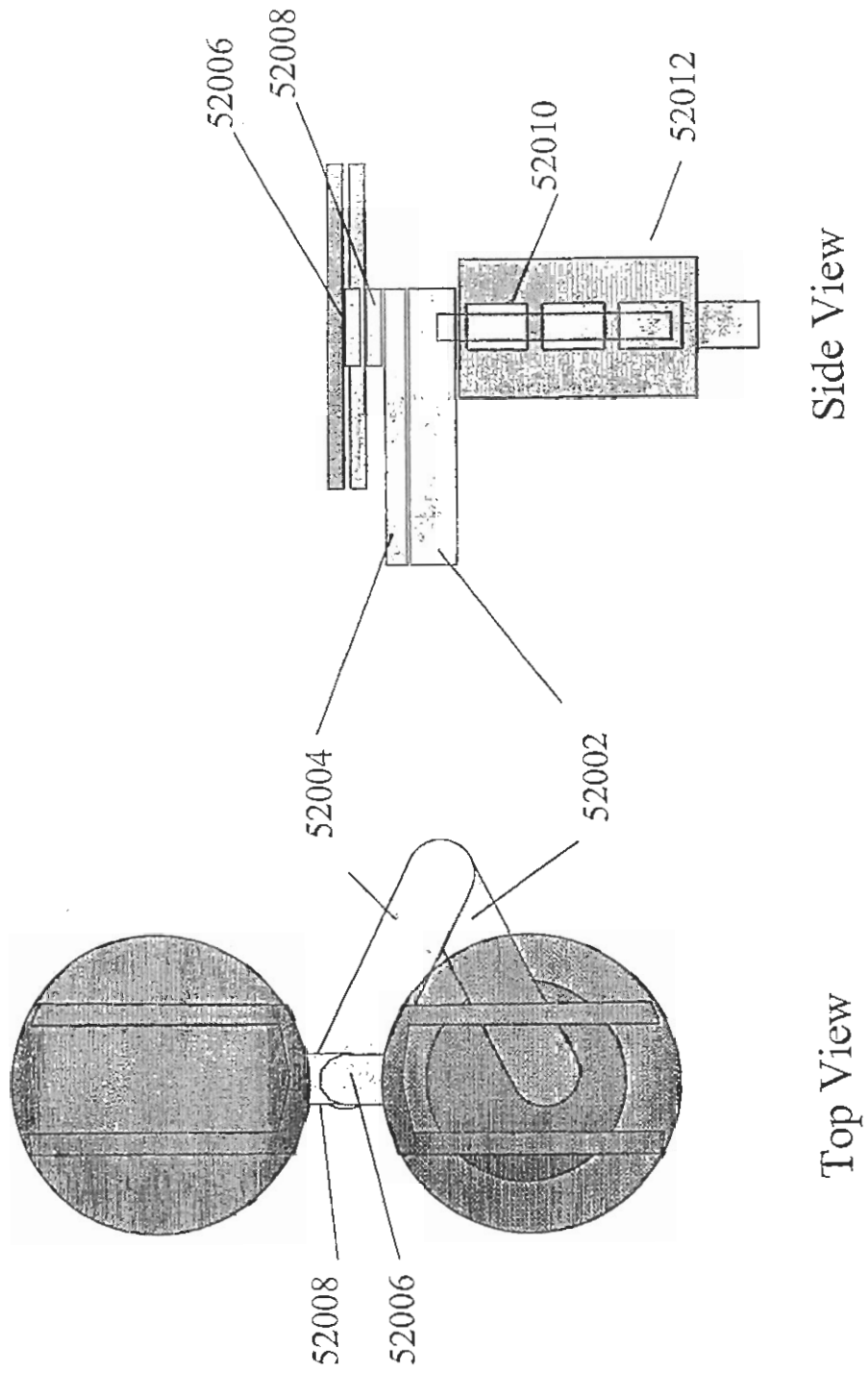
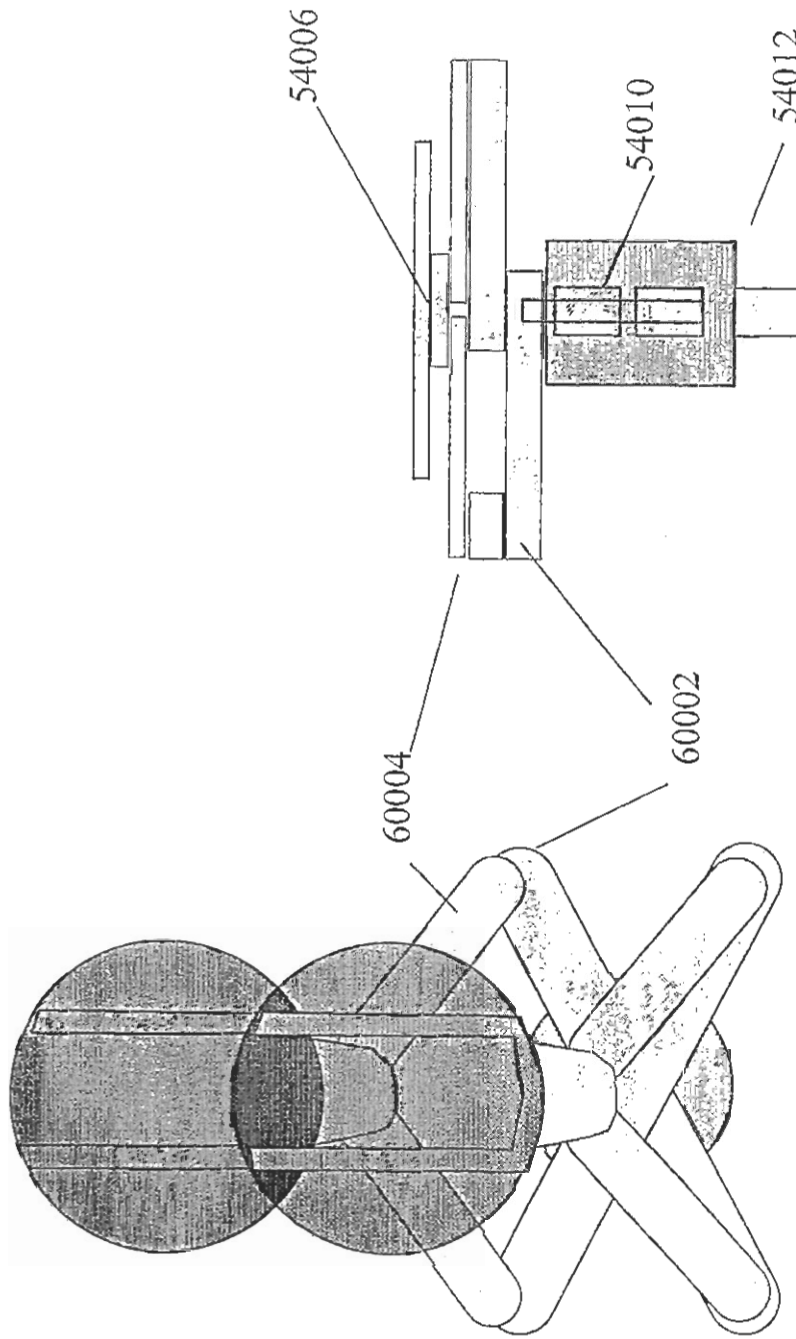


FIG. 52



Side View

Top View

FIG. 60